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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re patent application of:

Landon B. Vines et al.

Application No. 09/871,507

Filed: May 31, 2001

CMP POLISHER SUBSTRATE REMOVAL  
CONTROL MECHANISM AND METHOD

)  
) Before the Examiner  
)  
) Group Art Unit 1746  
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)  
) October 9, 2001  
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Associate P/A  
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ASSOCIATE POWER OF ATTORNEY AND  
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Assistant Commissioner for Patents  
Washington, D.C. 20231


Sir:

The undersigned attorney of record hereby requests that the correspondence address for  
the above-captioned application be changed to the following:

I hereby certify that this correspondence is being deposited with the  
United States Postal Service as first class mail in an envelope addressed  
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Date of Deposit: October 9, 2001

Name of Registered Representative: L. Scott Paynter

Signature: 

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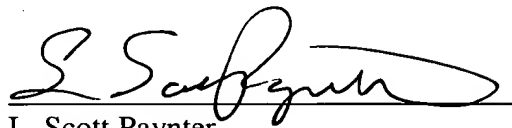
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Further, please recognize the following individuals as having associate power of attorney  
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Respectfully submitted,



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